

## Supplementary Information

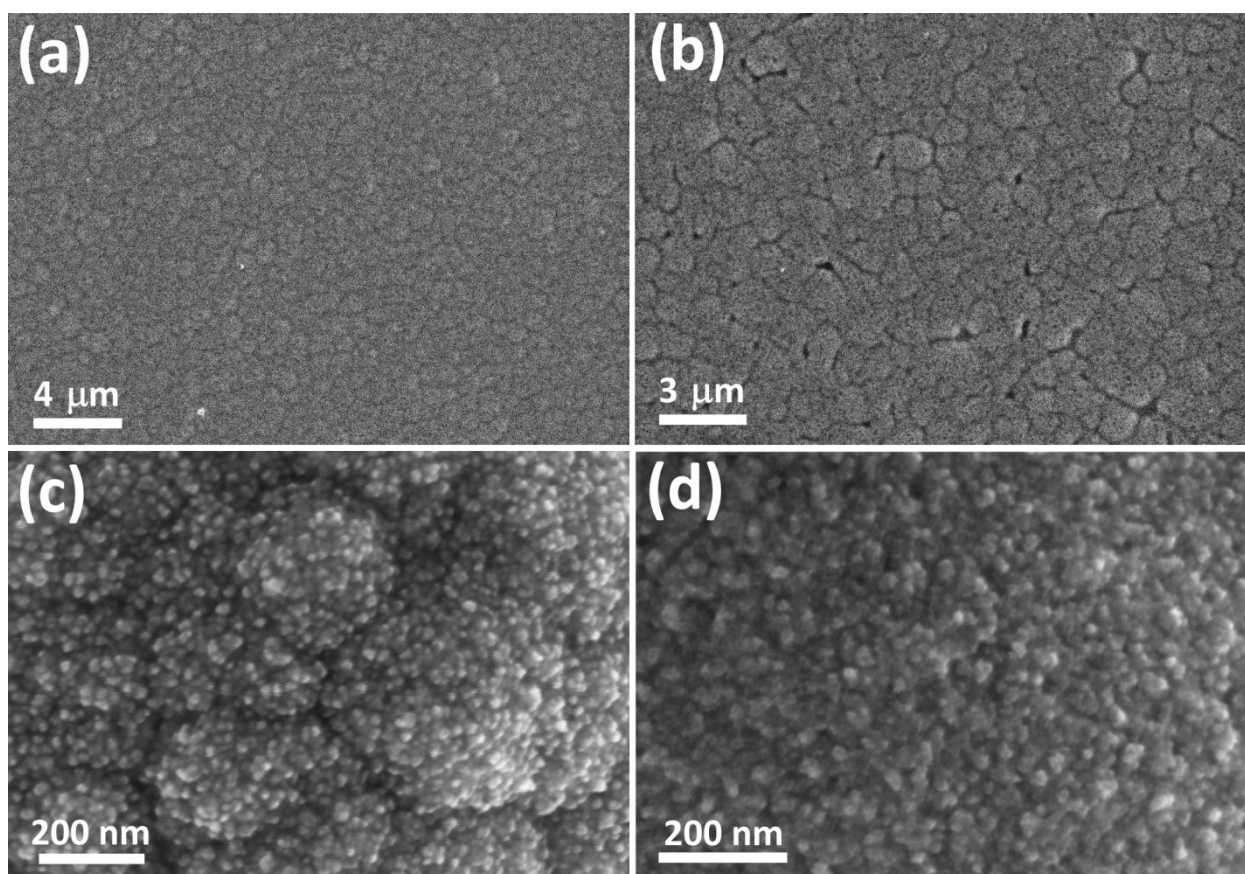
# Oxide Planar *p-n* Heterojunction Prepared by Low Temperature Solution Growth for UV-Photodetector Application

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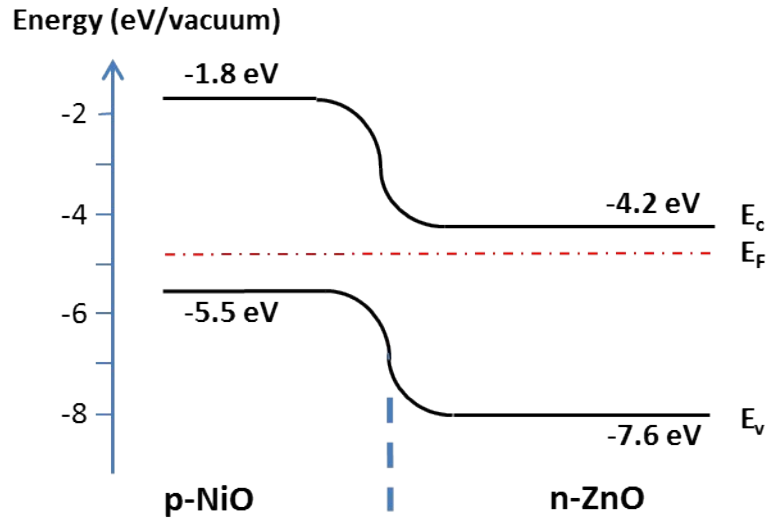
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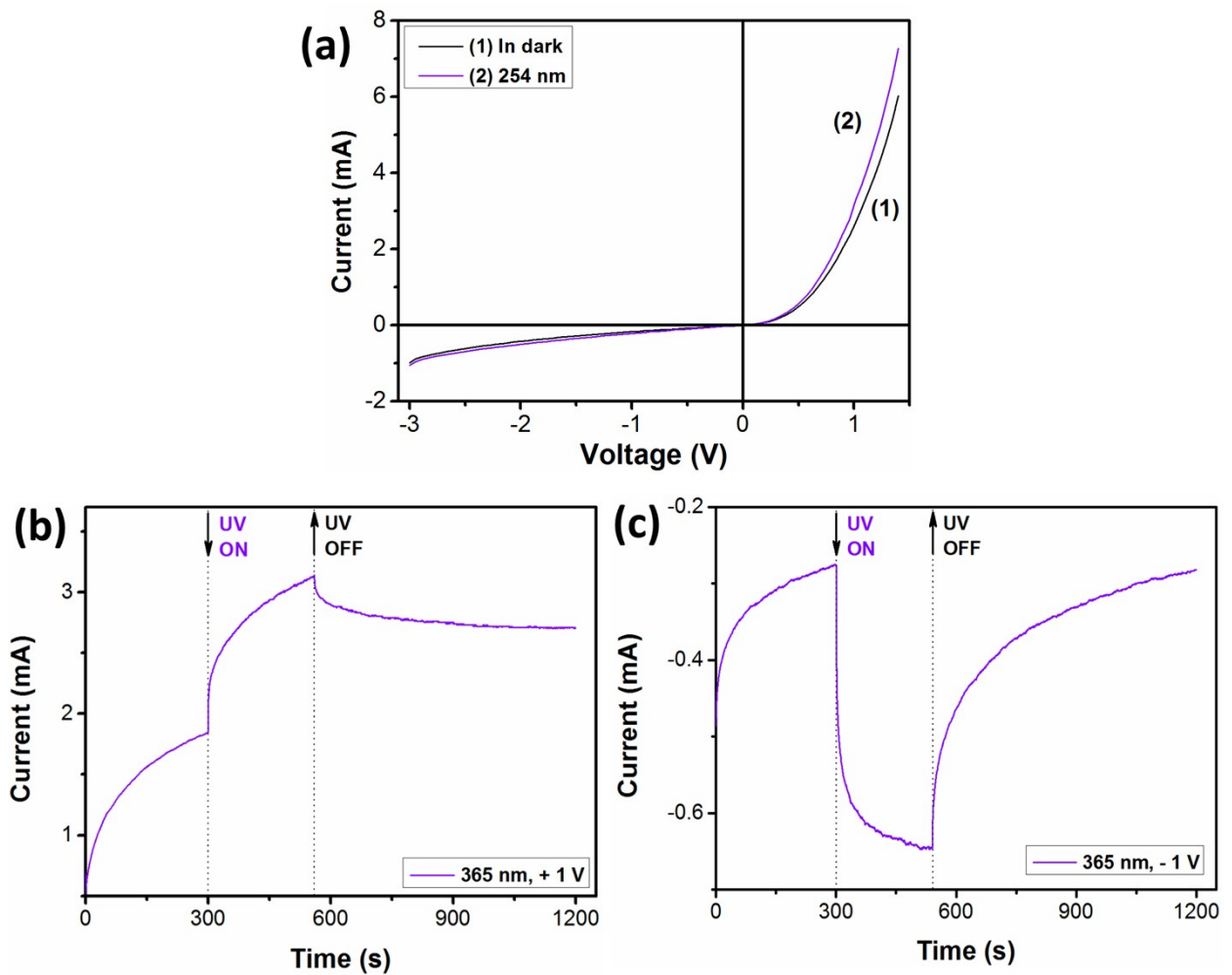
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**Figure S1.** SEM top-view images of the NiO deposited layer on ZnO/FTO/glass substrate at different magnifications.



**Figure S2.** Schematic energy band diagram of *p*-NiO/*n*-ZnO heterojunction at equilibrium.



**Figure S3.** (a) Typical current-voltage characteristics of the *p*-NiO/*n*-ZnO heterostructure based device in the dark and under UV illumination ( $\lambda = 254$  nm). (b,c) Transient UV ( $\lambda = 365$  nm) response at lower intensity at (b) +1 V and (c) -1 V applied voltage bias.